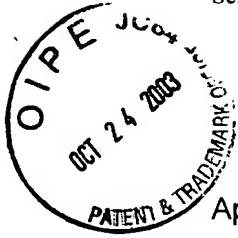


Serial No. 10/054,962



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Chun-Lien Su et al Attorney Docket No. : 4006-150
Serial No. : 10/054,962 Group Art Unit: 1765
Filed : 01/25/2002 Examiner: Chen, Kin Chan
Title: METHOD FOR CONTROLLING AND MONITORING A
CHEMICAL MECHANICAL POLISHING PROCESS

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RECEIVED
OCT 31 2003
TC 1700

Dear Sir:

This paper is in response to the Official Action mailed June 24, 2003.
Applicants respectfully submit the following amendments and comments in
connection with the above-named application.